



**N THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Wang et al.

Attorney Docket No.: NOVL085/  
NVLS-2875

Application No.: 10/785,235

Examiner: UNASSIGNED

Filed: February 23, 2004

Group: 2812

Title: PLASMA DETEMPLATING AND  
SILANOL CAPPING OF POROUS  
DIELECTRIC FILMS

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on April 8, 2005 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: 

Joyce L. Ferreira

**INFORMATION DISCLOSURE STATEMENT**

**37 CFR §§1.56 AND 1.97(b)**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is: (i) filed within three (3) months of the filing date of the above-referenced application, (ii) believed to be filed before the mailing date of a first Office Action on the merits, or (iii) believed to be filed before the mailing of a first Office Action after the filing of a Request for Continued Examination under §1.114. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NOVLP085).

Respectfully submitted,

BEYER WEAVER & THOMAS, LLP



Jeffrey K. Weaver  
Registration No. 31,314



<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)		Atty Docket No. NOVL085/NVLS-2875	Application No.: 10/785,235
		Applicant: Wang et al.	
		Filing Date February 23, 2004	Group 2812

#### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A1	4,882,008	1/21/89	Garza et al.			
	A2	6,329,017	12/11/01	Lu et al.			
	A3	2004/0099952	05/27/04	Goodner et al.			
	A4	2004/0102031	05/27/04	Kloster et al.			
	A5	2004/0185679	09/23/04	Ott et al.			
	A6						
	A7						
	A8						
	A9						
	A10						
	A11						

#### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	B1							

#### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	Tipton et al., "Method For Removal Of Porogens From Porous Low-K Films Using Supercritical Fluids", U.S. Patent No. 10/672,305, filed September 26, 2003, Office Action dated March 22, 2005
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.